

TOSHIYOSHI LAB.

MEMS/NEMS by Semiconductor Microfabrication



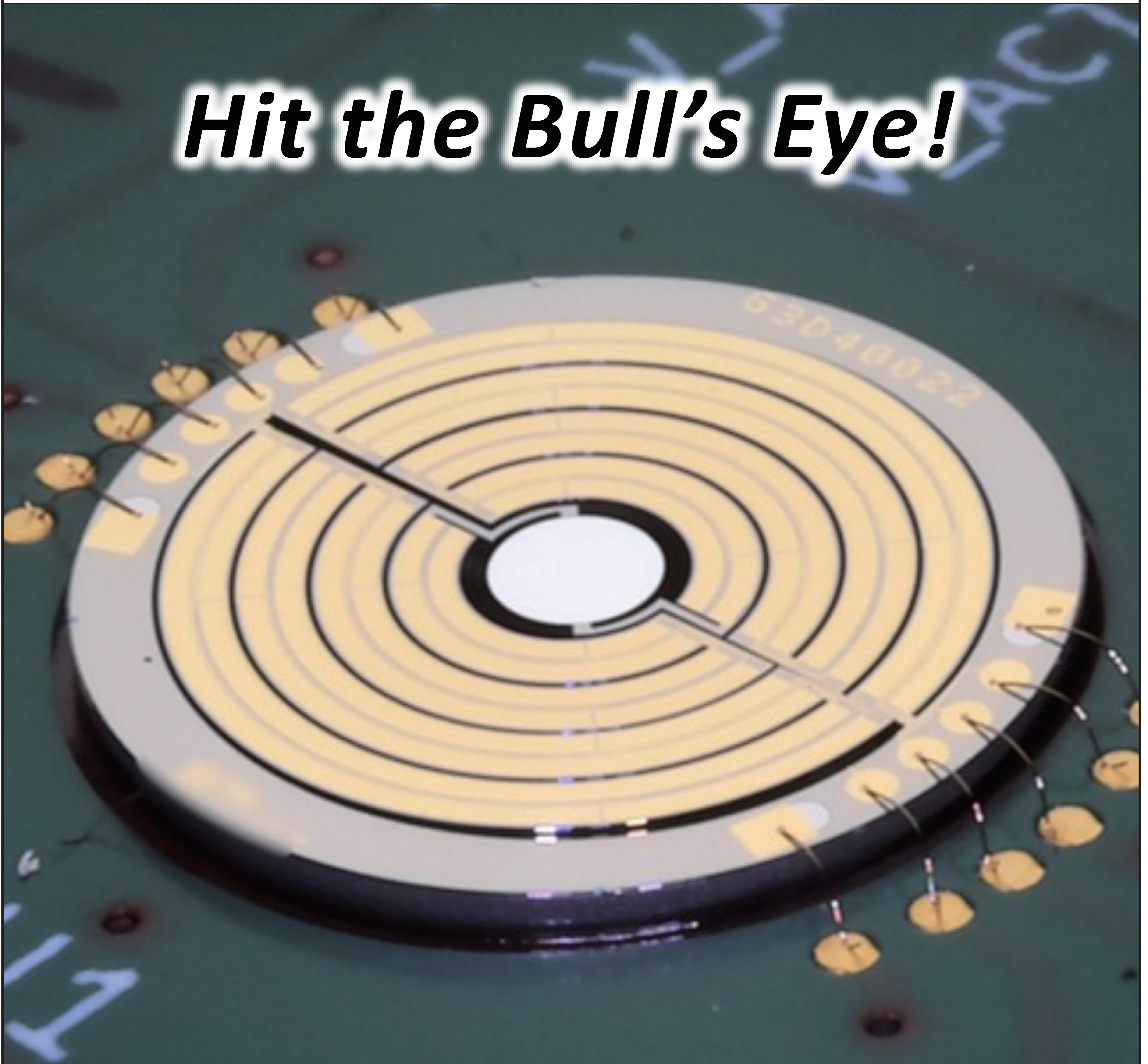
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Centre for Interdisciplinary Research on Micro-Nano Methods

Department of Electrical Engineering and Information Systems (EIS)
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MEMS/NEMS

<http://toshi.iis.u-tokyo.ac.jp/toshilab/>

Hit the Bull's Eye!



This work is performed as an international collaboration between IIS and SAL (Silicon Austria Labs).

Sara GUERREIRO, Markus BAINSCAB, Adrien PIOT, Rodrigo TUMOLIN ROCHA, Hiroshi TOSHIYOSHI, Alain BOSSEBOEUF, Takashi SASAKI, Anton LAGOSH, and Moridi MOHSSEN, "Optical and Environmental Characterization Bench for 2D Micromirrors," in Proc. Design, Test, Integration & Packaging of MEMS/MOEMS (DTIP 2023), Valletta, Malta, May 28-31, 2023.

